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Applicant's Name: Henry F. Erk et al.
Serial No.: 10/665,982 Examiner: Eric Brice Chen
Filing Date: 09/18/2003 Art Unit: 1765 Confirmation No.: 5374
Application Title: PROCESS FOR ETCHING SILICON WAFERS
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MEMC 02-0051 (3032.1) PATENT

REPLY UNDER 37 C.F.R. 1.116
EXPEDITED PROCEDURE
TECHNOLOGY CENTER 1700

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Henry F. Erk et al. Art Unit 1765
Serial No. 10/665,982
Filed September 18, 2003
Confirmation No. 5374
For PROCESS FOR ETCHING SILICON WAFERS
Examiner Eric B. Chen

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May 11, 2006

LETTER TO THE PATENT AND TRADEMARK OFFICE AFTER FINAL REJECTION

TO THE COMMISSIONER FOR PATENTS,

SIR:

In response to the final Office action mailed March 21, 2006, please consider the following remarks.

Remarks begin on page 2 of this Letter.